

**REPLY UNDER 37 CFR 1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER 2800**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

**In Re Application of:** Divakaruni et al.

**Conf. No.:** 1387

**Serial No.:** 10/707,388

**Art Unit:** 2891

**Filed:** 12/10/2003

**Examiner:** Fulk, Steven J.

**Title:** SILICIDE RESISTOR IN BEOL  
LAYER OF SEMICONDUCTOR  
DEVICE AND METHOD

**Docket No.:** FIS920030274  
(IBMF-0032)

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AFTER-FINAL REQUEST FOR RECONSIDERATION**

Sir:

**I. INTRODUCTORY COMMENTS:**

In response to the Final Office Action of December 07, 2006, please reconsider the above-referenced patent application in view of the following remarks: